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10/05/2001

PATENT NUMBER and  
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10052878	11/02/2001	438	600 <sup>+</sup>	281 <sup>4</sup>	PERALTA

**\*\*APPLICANTS:** Harshbarger William; Takehara Takako; Olsen Jeff; Qiu Regina;  
LeGrice Yvonne; Feng Guofu; Robertson Robert; Law Kam;

**\*\*CONTINUING DATA VERIFIED:**

THIS APPLICATION IS A CIP OF 08/500,728 07/11/1995 PAT 5,902,650  
WHICH IS A CON OF 09/249,041 02/12/1999 PAT 6,352,910

**\*\* FOREIGN APPLICATIONS VERIFIED:**

PG-PUB DO NOT PUBLISH ☐

RESCIND ☐

Foreign priority claimed ☐ yes ☐ no  
35 USC 119 conditions met ☐ yes ☐ no

ATTORNEY DOCKET NO

Verified and Acknowledged Examiners's initials

AMAT/827 - C 01

**TITLE :** Method of depositing amorphous silicon based films having controlled conductivity

U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED		
		Total Claims	Print Claim for O.G.	
Assistant Examiner				
ISSUE FEE		DRAWING		
Amount Due	Date Paid	Sheets Drawg.	Figs. Drawg.	Print Fig.
		Primary Examiner		
<input type="checkbox"/> <b>TERMINAL DISCLAIMER</b>		PREPARED FOR ISSUE		
		Application Examiner		
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